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TECHNOLOGY CENTER 2800⁸²³DATE: 13 MAY 2002TIME SENT: 1:12 P.M.TOTAL PAGES (INCLUDING COVER SHEET): 12ATTENTION: M. ESTRADACOMPANY NAME: U.S.P.T.O., ART UNIT # 2823TO FAX NUMBER: (703) 308-7722 (7724, 3431, 3432)

TRANSMITTING FROM: ROSENBERG, KLEIN & LEE

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OUR DOCKET NO. MR1035-820

YOUR REFERENCE

S/N 09/781,283**PLEASE NOTIFY US AT ONCE IF NOT RECEIVED PROPERLY.**

ADDITIONAL COMMENTS:


AMENDMENT FOR ENTRY

MR1035-820

CERTIFICATE OF FACSIMILE TRANSMISSION

I HEREBY CERTIFY that this Amendment responsive to the 13 February 2002
Office Action is being facsimile transmitted to Art Unit No. 2823 of the U.S. Patent and
Trademark Office on the date shown below.

FOR: ROSENBERG, KLEIN & LEE



David I. Klein

Registration No. 33,253

Date



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MR1035-820

#3/Amelto
J. Havel
5/14/02IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Jeng et al. :
Serial No. 09/781,283 : Art Unit No. 2823
File Date: 02/13/2001 : Examiner: M. Estrada
Title: Planarization Method Of Inter-Layer
Dielectrics And Inter-Metal Dielectrics

AMENDMENT

Box Non-fee Amendment
Assistant Commissioner for Patents
Washington, DC 20231

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Sir:

In response to the First Office Action dated 13 February 2002, please enter the following Amendment.

IN THE CLAIMS:

Please replace the following Claims with the clean copies thereof, as follows:

Claim 1 should be replaced with:

1. (Once Amended) A planarization method of inter-layer dielectrics, comprising the steps of:

Sub
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